

(Use several sheets if necessary)

Application Number 09/957,000  
Unassigned

**Filing Date**  
**Filed Herewith**

Group Art Unit	1765
Unassigned	

[illegible][illegible]

SA	1	I.W. Rangelow, "High-resolution tri-level process by downstream-microwave RF-biased etching," SPIE, Vol.1392, Advanced Techniques for Integrated Circuit Processing (1990), pp. 180-184.
SA	2	K. Tsujimoto et al., "A New Side Wall Protection Technique in Microwave Plasma Etching Using a Chopping Method", Abstracts of the 18th (1986 International) Conference on Solid State Devices and Materials, Tokyo, 1986, pp. 229-232.

EXAMINER Shamim Ahmed

DATE CONSIDERED 3/6/03

**EXAMINER:** Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

